
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Patton et al.

Atty Dkt No.: NOVLP016C1/NVLS-
000403C1

Application No.: UNASSIGNED

Examiner: UNASSIGNED

Filed: HERewith

Group: UNASSIGNED

Title: SEQUENTIAL STATION TOOL FOR WET
PROCESSING OF SEMICONDUCTOR
WAFERS

**INFORMATION DISCLOSURE STATEMENT
37 CFR §§1.56 AND 1.97(b)**

Mail Stop Patent Application
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Dear Sir:

The references listed in the attached PTO Form 1449 may be material to examination of the above-identified patent application. Applicants submit the list of these references in compliance with their duty of disclosure pursuant to 37 CFR §§1.56 and 1.97. The Examiner is requested to make these references of official record in this application. The above-identified application is a continuation of prior application U.S. Patent Application No. 09/828,371. This prior application is being relied upon for an earlier filing date under 35 U.S.C. § 120. Because the listed references were either cited by the PTO, or submitted to the PTO in the prior application, under 37 CFR § 1.98(d) Applicants submit that copies need not be provided.

This Information Disclosure Statement is not to be construed as a representation that a search has been made, that additional information material to the examination of this application does not exist, or that these references indeed constitute prior art.

This Information Disclosure Statement is: (i) filed within three (3) months of the filing date of the above-referenced application, (ii) believed to be filed before the mailing date of a first Office Action on the merits, or (iii) believed to be filed before the mailing of a first Office Action after the filing of a Request for Continued Examination under §1.114. Accordingly, it is believed that no fees are due in connection with the filing of this Information Disclosure Statement. However, if it is determined that any fees are due, the Commissioner is hereby authorized to charge such fees to Deposit Account 500388 (Order No. NOVLP016C1).

Respectfully submitted,

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| Form 1449 (Modified) Information Disclosure Statement By Applicant (Use Several Sheets if Necessary) | Atty Docket No. | Application No.: |
| | NOVLP016C1/ NVLS- | UNASSIGNED |
| | 000403C1 | |
| | Applicant: | |
| | Patton, et al. | |
| | Filing Date | Group |
| | HEREWITH | UNASSIGNED |

U.S. Patent Documents

| Examiner Initial | No. | Patent No. | Date | Patentee | Class | Sub-class | Filing Date |
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| | A2 | 6,267,853 | 7/01 | Dordi et al. | | | |
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Foreign Patent or Published Foreign Patent Application

| Examiner Initial | No. | Document No. | Publication Date | Country or Patent Office | Class | Sub-class | Translation | |
|------------------|-----|--------------|------------------|--------------------------|-------|-----------|-------------|----|
| | | | | | | | Yes | No |
| | B1 | WO/32835 | 08.06.00 | PCT | | | X | |
| | B2 | WO 99/41434 | 19.08.99 | PCT | | | X | |
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Other Documents

| Examiner Initial | No. | Author, Title, Date, Place (e.g. Journal) of Publication |
|------------------|-----|--|
| | C1 | |
| | | |
| | | |
| Examiner | | Date Considered |

Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.